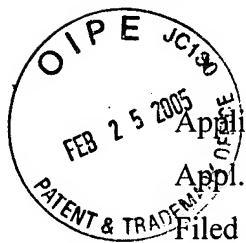


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PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Kamal Kisho Goundar
Appl. No. : 10/616,163
Filed : July 9, 2003
For : METHOD OF FORMING
SILICON CARBIDE FILMS
Examiner : Monica D Harrison
Group Art Unit : 2829

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

February 22, 2005

(Date)

Katsuhiro Arai, Reg. No. 43,315

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed September 22, 2004, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.

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